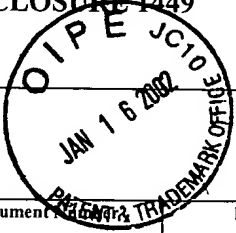


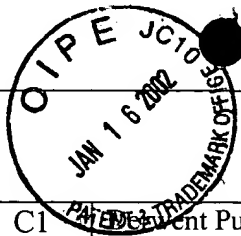
INFORMATION DISCLOSURE 1449 	Docket No.: MCA-389 PC/US	Application No.: 09/890,109
	Applicant: Cheng, et al.	
	Filing Date: July 26, 2001	Group Art Unit: 1723

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	*B6	EP 0 343 247 ✓	11/89	EPO				
	B7	EP 0 559 149 ✓	09/93	EPO				
	B8	EP 0 803 281 ✓	10/97	EPO				
✓	B9	EP 0 855 212 ✓	07/98	EPO				
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	B12	WO 00/44480 ✓	08/00	EPO				
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* Indicates a cite that has been previously forwarded to the USPTO and is not enclosed.